

10/587427
IAP11 Rec'd PCT/PTO 26 JUL 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: Not yet assigned
Applicants: Eri TSUKADA, et al.
Filed Internationally: January 19, 2005
US National: Herewith
Title: METHOD FOR PRODUCING SILICON NITRIDE FILMS AND
SILICON OXYNITRIDE FILMS BY CHEMICAL VAPOR
DEPOSITION
TC/A.U.: Unknown
Examiner: Unknown
Docket No.: Serie 6497
Customer No.: 000040582

INFORMATION DISCLOSURE STATEMENT

Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with the duty of disclosure as set forth in 37 C.F.R. § 1.56, Applicants hereby submit the following information in conformance with 37 C.F.R. §§ 1.97 and 1.98. Pursuant to 37 C.F.R. § 1.98, a copy of each of the non-US patent documents cited on the attached PTO Form 1449 is enclosed.

No fee is due at this time in accordance with 37 C.F.R. § 1.97. However, the Commissioner is hereby authorized to charge any appropriate fees under 37 C.F.R. §§ 1.16, 1.17 and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 01-1375.

To assist the Examiner, the documents are listed on the attached form PTO-1449. It is respectfully requested that an Examiner-initialed copy of this form be returned to the undersigned. This paper is submitted in duplicate.

Respectfully submitted,



Date: July 26, 2006

Linda K. Russell, Reg. No. 34,918

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(USE SEVERAL SHEETS IF NECESSARY)

APPLICANT(S)

Not yet assigned

Eri TSUKADA, et al.

FILING DATE

GROUP

Herewith

Unknown

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	C1	International Search Report for PCT/IB2005/000170
	C2	Patent Abstracts of Japan, vol. 1996, no. 01, January 31, 1996 & JP 07 235535, September 54, 1995
	C3	M. Tanaka et al., Journal of the Electrochemical Society, Volume 147, p. 2284 (2000)
	C4	R. K. Laxman et al., Proceedings of the VMIC Conference, p. 568 (1998)

Examiner

Date Considered

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.